Bridge
Technology

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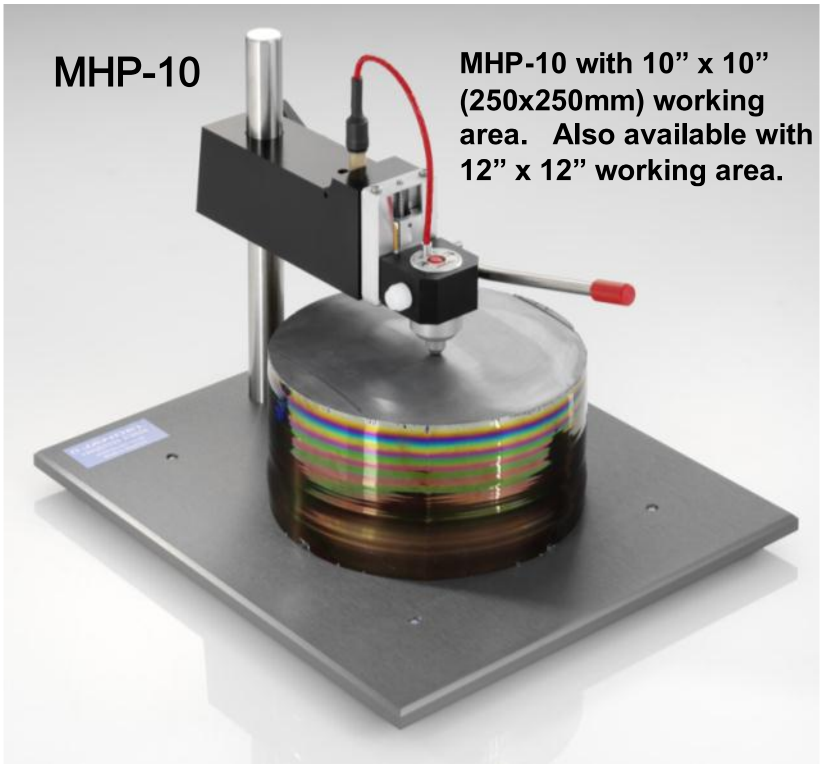
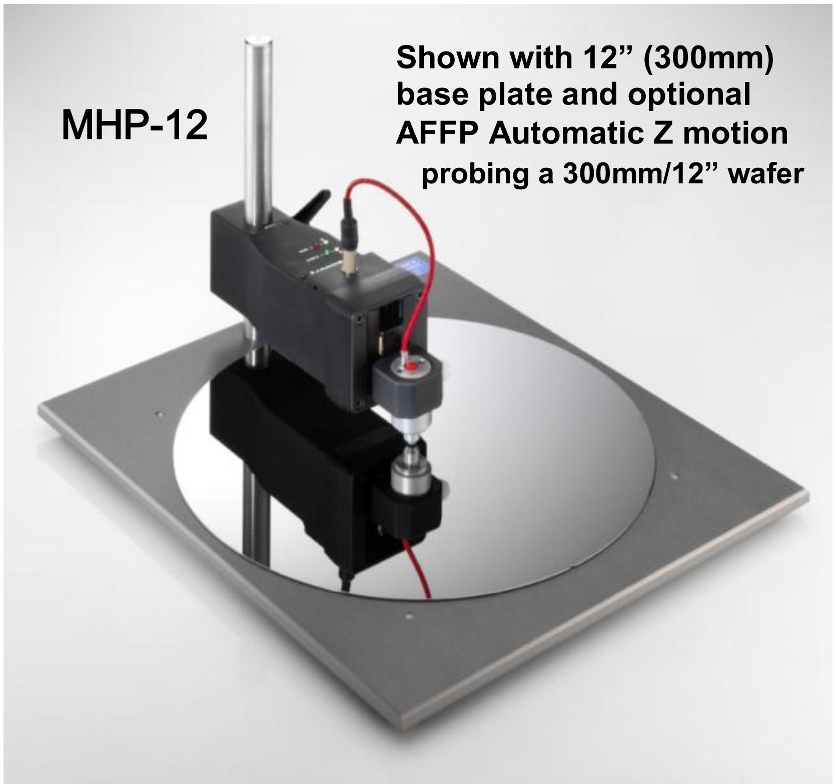
Jandel Multi Height Probe

- **Allows probing of wafers, ingots, or samples of widely varying dimensions**
- **Locking mechanism allows the arm to be moved up and down the steel pole and locked to suit any sample height**
- **Plug attached to the arm prevents the wiring from getting entangled with**
- **samples, fingers etc.**
- **Smooth base for positioning samples**
- **Includes one Jandel Cylindrical probe head**
- **Micro-switch prevents current from turning on until after probe head is in contact with the substrate.**



MHP-10

MHP-10 with 10” x 10” (250x250mm) working area.   Also available with 12” x 12” working area.

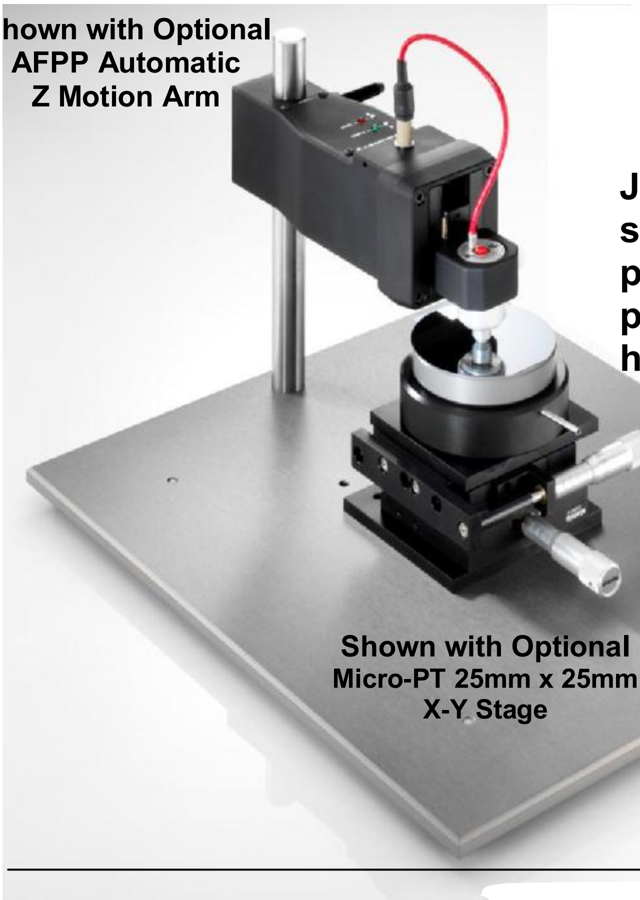


MHP-12

Shown with 12” (300mm) base plate and optional AFFP Automatic Z motion probing a 300mm/12” wafer

- **Pricing is the same for either 10” or 12” base plate**
- **Available with high temperature Cylindrical probe for use in probing with a hot chuck (not supplied) at elevated temperatures. The Cylindrical probe in the standard configuration can withstand temperatures from LN2 up to 120C.**
- **A longer post is available for probing taller materials**
- **The manual Z motion arm shown above can be configure for use with the 10” or 12” working area base plate. The AFPP motorized Z arm requires the 12” working area base plate if the probe is to be centered over the working area.**

Multi Height Probe Sample Stage Options



Shown with Optional AFPP Automatic Z Motion Arm

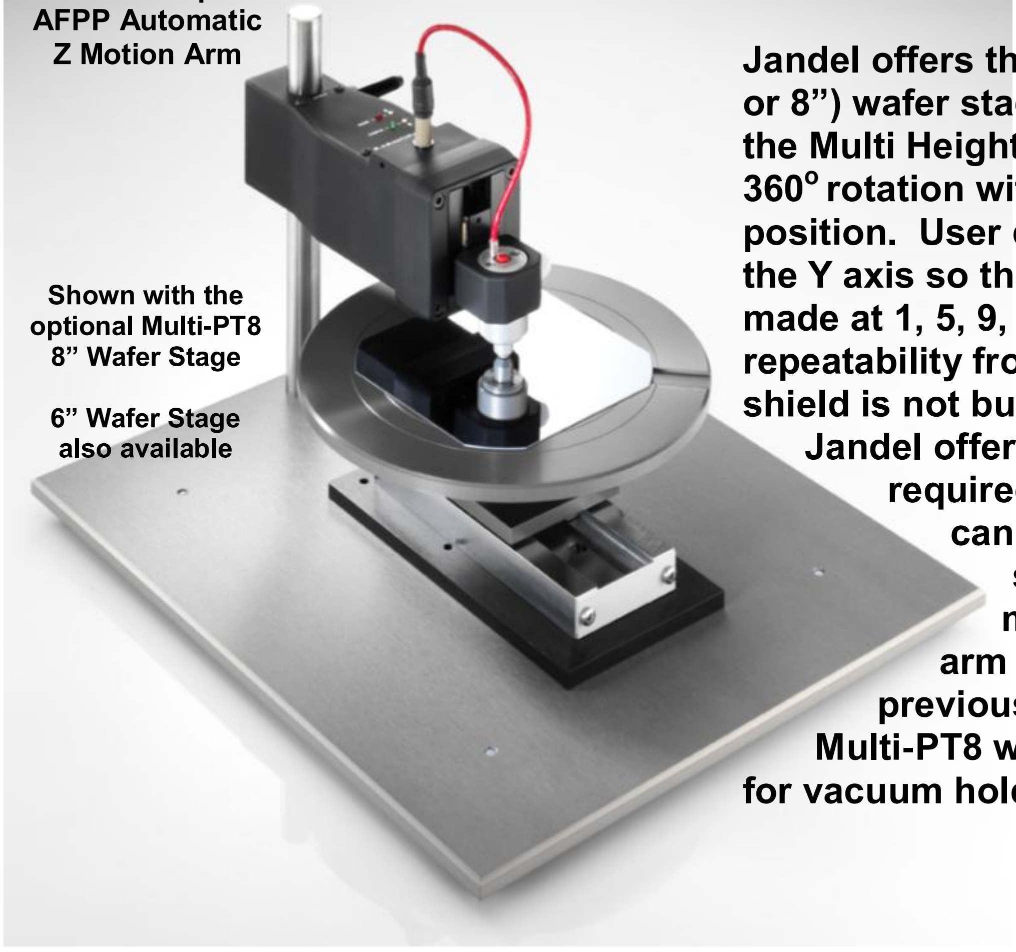
Shown with Optional Micro-PT 25mm x 25mm X-Y Stage

Micro-PT Stage Option

Jandel offers the Micro-PT 25mm (1”) travel X-Y stage with a 3” diameter wafer chuck for use when positioning small samples under the four point probe needles. Included is the facility for vacuum hold-down.

If Jandel knows in advance that the Multi Height Probe may be upgraded in the future to add a sample stage, it can be supplied at no additional charge with the pre-drilled hole pattern. Otherwise, the base plate must be returned to the factory to mount the 1” travel stage.

Multi-PT6 & Multi-PT8 Wafer Stage Options



Shown with Optional AFPP Automatic Z Motion Arm

Shown with the optional Multi-PT8 8” Wafer Stage

6” Wafer Stage also available

Jandel offers the Multi-PT6 and Multi-PT8 (6” or 8”) wafer stages as an option for use with the Multi Height Probe. The wafer stage has 360° rotation with detents at each 90 degree position. User defined detents are set along the Y axis so that measurements can be made at 1, 5, 9, or more positions with 1mm repeatability from wafer to wafer. A light shield is not built into the system, however, Jandel offers a black cloth light shroud if required. The probe Z motion arm can be either the motorized version as shown here, or the manually raised and lowered arm as shown at the top of the previous page. The Multi-PT6 and Multi-PT8 wafer stages include a facility for vacuum hold-down for the wafer.